



PATENT

In the United States Patent and Trademark Office

Applicant: Adrian KIERMASZ)	Examiner: M. Rachuba
Applicant's Reference: LAM2P452)	Group Art Unit: 3723
Application No. 10/743,923)	Date: June 13, 2006
Filed: December 22, 2003)	
Title: LINEAR CHEMICAL MECHANICAL PLANARIZATION (CMP) SYSTEM AND METHOD FOR PLANARIZING A WAFER IN A SINGLE CMP MODULE)	Conf. No. 9016 (Notice of Allowance mailed 03/13/06)

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on June 13, 2006.

Signed:

Diane Schwanbeck

Separate Letter to the Official Draftsperson

Commissioner for Patents
Post Office Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Applicant hereby attaches four (4) sheets of formal replacement drawings (Figures 1, 2A, 2B, and 3A-3C) for the above-identified patent application. In the event the Draftsperson has any questions concerning the formal drawings, he or she is respectfully requested to contact the undersigned. If any fees are due in connection with the filing of these drawings, then please charge such fees to our Deposit Account No. 50-0805 (Order No. LAM2P452).

Respectfully submitted,
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